

Prof. Tae-Gon Kim

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Tae-Gon Kim is a Professor in the Department of Materials and Components Convergence Engineering at Hanyang University ERICA, South Korea. He received his B.S., M.S., and Ph.D. degrees in Materials Science and Engineering from Hanyang University. Prior to joining academia, he spent over a decade at imec in Belgium (2008–2019) as a Postdoctoral Fellow and Senior Researcher, leading numerous cutting-edge R&D projects in advanced cleaning, CMP, and metrology & inspection (MI) for next-generation logic, STT-MRAM, advanced interconnects, and 3D heterogeneous packaging. Since joining Hanyang University ERICA in 2019, his research group has focused on wet cleaning, chemical mechanical planarization (CMP), surface/interface characterization, and hybrid bonding. Prof. Kim serves as the Conference Secretary for ICPT 2026, a Program Committee member for the Surface Preparation and Cleaning Conference (SPCC), and the Committee Manager for ISO TC201/SC9 (Scanning Probe Microscopy). He also actively contributes to the community as a board member of the Korea Cleaning Association and the Korean Society of Surface Analysis.